

12/11/03

Sheet 1 of 5

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE					ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/005,322 10/134419		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT John T. Moore et al.			
					PRIORITY FILING DATE November 26, 2001		PRIORITY GROUP 2815	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
MEW	AA	5,219,788	6/93	Abernathy et al.				
	AB	5,045,847	9/91	Tarui et al.				
	AC	5,045,345	9/91	Singer				
	AD	4,996,081	2/91	Eltul et al.				
	AE	3,884,698	5/75	Kakihama et al.				
	AF	5,518,946	5/96	Kuroda				
	AG	5,489,542	2/96	Iwai et al.				
	AH	4,330,569	5/82	Gulett et al.				
	AI	4,499,656	2/85	Fabien et al.				
	AJ	5,554,418	9/96	Ito et al.				
↓	AK	5,926,739	7/99	Rofson et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country		Class	Subclass	Translation
MEW	AL	401086562	3/89	Japan				Yes
	AM	362137854	6/87	Japan				No
	AN	2129217	5/84	Great Britain				
	AO	2170649	8/86	Great Britain				
↓	AP	2145243	3/85	Great Britain				
↓	AQ	403075158	3/91	Japan				
OTHER REFERENCES (including Author, Tide, Date, Pertinent Pages, Etc.)								
MEW	AR		Silicon Proc. for VLSI; 177-178; Vol. I; S. Wolf					
MEW	AS		Silicon Proc. for VLSI; 191-193; Vol. I; S. Wolf					
EXAMINER	Matthew E. Warner			DATE CONSIDERED		12/7/04		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE					ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/995,373		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT John T. Moore et al.		10/1734419	
					PRIORITY FILING DATE November 26, 2001	PRIORITY GROUP 2815		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
Mew	AA	4,874,716	10/89	Rao				
	AB	5,587,344	12/96	Ishikawa				
	AC	4,439,270	3/84	Powell et al.				
	AD	5,773,325	6/98	Teramoto				
	AE	5,904,523	5/99	Feldman et al.				
	AF	5,891,793	4/99	Gardner et al.				
	AG	5,795,821	8/98	Bacchetta et al.				
	AH	5,918,147	6/99	Filipiak et al.				
	AI	5,882,978	3/99	Srinivasan et al.				
	AJ	4,612,629	9/86	Harari				
↓	AK	5,831,321	11/98	Nageyama				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
	AL						Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
Mew	AR		Silicon Proc. for VLSI; 37-38; 598-599; Vol. 2; S. Wolf					
Mew	AS		Electronic Materials Science: For Integrated Circuits; 1990 ©; Mayer et al; pp. 269-274; Pub. 1990					
EXAMINER	Matthew C. Wanen			DATE CONSIDERED		12/17/04		
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/995,372		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT John T. Moore et al.	10/734419		
					PRIORITY FILING DATE November 26, 2001	PRIORITY GROUP 2815		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
MLW	AA	3,549,411	12/70	Bean				
	AB	4,446,194	5/84	Candelaria				
	AC	4,485,553	12/84	Christian				
	AD	4,543,707	10/85	Ito et al.				
	AE	5,098,865	3/92	Machado et al.				
	AF	5,160,998	11/92	Itoh et al.				
	AG	5,306,946	4/94	Yamamoto				
	AH	5,442,223	8/95	Fujii				
	AI	5,523,616	6/96	Den				
	AJ	5,756,404	5/98	Friedreich et al.				
	AK	5,834,374	11/98	Cabral Jr. et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
	AL						Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
MLW	AR		Intrinsic Stress in Silicon Nitride and Silicon Dioxide Films Prepared by Various Deposition Techniques; 1988 IEEE Internat. Sympos. On Electrical Insulation, Boston, MA; June 5-8, 1988; 1 page; Kanicki, J. et al.					
MLW	AS		Passivation of GaAsFET's with PECVD Silicon Nitride Films of Different Stress States; IEEE Transactions on Electron Devices; Vol. 35, No. 9; Sept. 1988; pp. 1412-1418					
EXAMINER	Matthew G. Warner			DATE CONSIDERED	12/7/04			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE					ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/896,372 <i>107734419</i>		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT John T. Moore et al.			
					PRIORITY FILING DATE November 26, 2001	PRIORITY GROUP 2015		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate
<i>Mew</i>	AA	4,695,872	9/87	Chatterjee				
	AB	5,178,016	1/93	Dauenhauer et al.				
	AC	5,985,771	11/99	Moore et al.				
	AD	3,649,884	3/72	Haneta				
	AE	4,868,632	9/89	Hayashi				
	AF	5,304,829	4/94	Mori et al.				
	AG	5,925,494	7/99	Horn				
	AH	4,075,367	2/78	Gulett				
	AI	4,732,858	3/88	Brewer et al.				
	AJ	6,300,253	10/01	Moore, John T.				
<i>V</i>	AK	4,698,787	10/87	Mukherjee et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
	AL						Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
<i>Mew</i>	AR	Silicon Nitride Overcoats for Thin Film Magnetic Recording Media; IEEE Transactions on Magnetics; Vol 27. No. 6, Nov. 1991; pp. 5070-5072						
	AS							
EXAMINER <i>Matthew E. Wana</i>			DATE CONSIDERED <i>12/7/04</i>					
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>								

EL979950548

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					ATTY. DOCKET NO. MI22-2463	PRIORITY SERIAL NO. 09/899,312 <i>10/734419</i>	
					APPLICANT John T. Moore et al.		
					PRIORITY FILING DATE November 26, 2001		PRIORITY GROUP 2815
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>new</i>	AA	4,939,559	07/90	DiMaria et al.		1	
	AB	6,140,181	10/00	Forbes et al.			
	AC	6,143,627	11/00	Robinson			
	AD	5,877,069	03/99	Robinson			
	AE	6,093,956	07/00	Moore et al.			
	AF	6,103,619	08/00	Lai			
	AG	6,263,241	07/01	Pan			
	AH	6,420,777		Lam et al.			
	AI	6,417,559	07/02	Moore et al.			
	AJ	5,041,888	08/91	Possin et al.			
	AK	6,143,662	11/00	Rhodes et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
							No
	AL						
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
	AS						
EXAMINER	<i>Matthew C. Warner</i>			DATE CONSIDERED	<i>12/7/04</i>		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							